

Semiconductor wafer handler

ABSTRACT OF THE INVENTION

5 A semiconductor wafer handler comprises a ring (70) attached to a hub (80) by a plurality of spokes (90). Vacuum is applied to the surface of the semiconductor wafer through orifices (100) containing in the ring (70). Water and/or nitrogen can be applied to the surface of the semiconductor 10 wafer through orifices (110) contained in the spokes (90).